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# Electronic Filing System (EFS) Data

## Electronic Patent Application Submission

### USPTO Use Only

EFS ID: 63071

Application ID: 10680783



Title of Invention: HIGH-PRESSURE CHAMBER FOR A  
SEMICONDUCTOR WAFER

First Named Inventor: William Jones

Domestic/Foreign Application: Domestic Application

Filing Date: 2003-10-06

Effective Receipt Date: 2004-06-22

Submission Type: Information Disclosure  
Statement

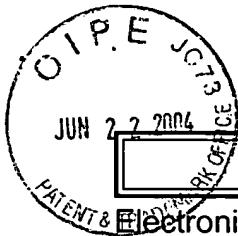
Filing Type:

Confirmation number: 5859

Attorney Docket Number: NONE

Total Fees Authorized:

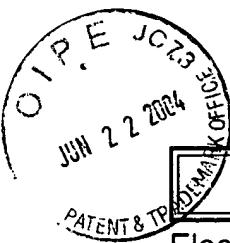
Digital Certificate Holder: cn=Thomas B. Haverstock,ou=Registered Attorneys,ou=Patent and  
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Certificate Message Digest: ab4bce6b9127819148fc68a1715a12c75de85264



## TRANSMITTAL

Electronic Version v1.1  
Stylesheet Version v1.1.0

Title of Invention	HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER	
Application Number:	10/680783 	
Date:	2003-10-06	
First Named Applicant:	William D.	
Confirmation Number:	5859	
Attorney Docket Number:		
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<p>I, the undersigned, certify that I have viewed a display of document(s) being electronically submitted to the United States Patent and Trademark Office, using either the USPTO provided style sheet or software, and that this is the document(s) I intend for initiation or further prosecution of a patent application noted in the submission. This document(s) will become part of the official electronic record at the USPTO.</p>		
Submitted by:	Elec. Sign.	Sign. Capacity
Thomas B. Haverstock Registered Number: 32571	/tbh/	Attorney
Documents being submitted	Files	
us-ids	SSI04001-usidst.xml	
	us-ids.dtd	
	us-ids.xsl	
Comments		



## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	HIGH-PRESSURE CHAMBER FOR A SEMICONDUCTOR WAFER
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Application Number: 10/680783



Confirmation Number: 5859

First Named Applicant: William Jones

Attorney Docket Number:

Search string: ( 5186594 or 5769588 or 5906866 or 5975492  
or 6122566 or 6355072 or 6454519 or  
20030205510 or 20040020518 ).pn.

### US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5186594	1993-02-16	Toshima et al.			
	2	5769588	1998-06-23	Toshima et al.			
	3	5906866	1999-05-25	Webb			
	4	5975492	1999-11-02	Brenes			
	5	6122566	2000-09-19	Nguyen et al.			
	6	6355072	2002-03-12	Racette et al.	B1		
	7	6454519	2002-09-24	Toshima et al.	B1		

### US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20030205510	2003-11-06	Jackson	A1		
	2	20040020518	2004-05-02	DeYoung et al.	A1		

### Signature

Examiner Name	Date
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